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PATENT Attorney Docket: 90738

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#### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Ke U.S. Pai	ent Application	)
Applicant(s):	Satoshi Komiya et al.	) Confirmation No.: 1669
Serial No.:	10/049,971	) I hereby certify that this ) correspondence is being deposited ) with the United Postal Service as first
Filed:	October 3, 2003	class mail in an envelope addressed to: Mail Stop PATENT APPLICATION /
For:	SILICON WAFER AND METHOD FOR MANUFACTURE THEREOF, AND METHOD OF EVALUATION OF SILICON WAFER	Commissioner for Patents / P.O. Box 1450 / Alexandria, Virginia 22313-1450, on January 20, 2004  Gerald T. Shekleton Reg. No. 27,466
Examiner:	Not Yet Assigned	)
Art Unit:	1765	)

#### INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

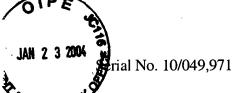
Sir:

Pursuant to 37 C.F.R. §1.97, a list of documents is disclosed on the attached Form PTO-1449 that may be material to the examination of this application.

No inferences should be drawn that the attached list represents a comprehensive investigation, or that any material disclosed is equivalent to the subject invention. In addition, none of the documents that have publication dates prior to the priority date of the above application anticipate the invention in this application.

The cited document(s) disclose numerous specific features. There has been no attempt to list each and every feature disclosed by each document. The Examiner is requested to review the document(s) and determine the extent of the materiality of the document disclosures with respect to the present invention.

The discussion of any art and the citation of any document(s) herein is not to be construed



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as an admission that the art or document disclosure is necessarily within the invention field of endeavor, that the art or document disclosure is necessarily prior in time to a particular date which may be relevant to the instant patent application, and/or that the art or document disclosure is otherwise necessarily prior art as defined by the patent law with respect to the instant invention and application.

Also, there is reserved the right to later set forth how the instant invention is distinguished over the disclosure of any document or other art, including the disclosures of the art and document(s) recited herein, that may be cited by the Examiner in rejecting a claim in the instant patent application. The recitation herein of the art and document(s) is not to be construed as an assertion that more pertinent art could not possibly be in existence.

Respectfully submitted,

WELSH & KATZ, LTD.

well To Shall

Gerald T. Shekleton

Registration No. 27,466

Dated: January 20, 2004
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(Rev. 5/92) Comparable to Form PTO-144	5/92) U.S. Department of Commerce arable to Patent and Trademark Office			Atty. Docket No. 90738		Serial No. 10/049,971		
	(Use several sheets if necessity)							
				Applicant Satoshi Komiya et al.				
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